

**Title of Abstract:**

**High performance 60nm CMOS technology enhanced with BST (body-slightly-tied) structure SOI and Cu/Low-k (k=2.9) interconnect for microprocessors**

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**Abstract:**

We have developed high performance / low active power CMOS technology for microprocessor products. This features 1) drive current enhancement with high-dose low-energy I/I for S/D extension, 2) body-slightly-tied (BST) CMOS/SOI with partial trench isolation and local channel doping, 3) Cu interconnect with low-k (k=2.9) dielectric. BST CMOS/SOI shows negligible history effect, therefore existing circuit and layout design of bulk CMOS are reusable while enjoying all advantages of SOI.